

Contents

Preface *xi*

Julien Bachmann

The Past of Energy Conversion *xi*

The Future of Energy Conversion *xi*

Technical Ingredients Needed *xiii*

Scope of This Book *xiv*

Photovoltaics: Strategies, Length Scales, and ALD *xv*

Electrochemical Energy Storage: Principles, Chemistries, and ALD *xvii*

Other Energy Conversion Strategies Based on Interfaces *xix*

References *xx*

List of Contributors *xxiii*

Part I Introduction to Atomic Layer Deposition *1*

1 Basics of Atomic Layer Deposition: Growth Characteristics and Conformality *3*

Jolien Dendooven and Christophe Detavernier

1.1 Atomic Layer Deposition *3*

1.1.1 Principle of ALD *3*

1.1.2 ALD Growth Characteristics – Linearity, Saturation, and ALD Window *5*

1.1.3 Plasma-Enhanced ALD *8*

1.1.3.1 Plasma Configurations for Plasma-Enhanced ALD *9*

1.1.3.2 Reactions in Plasma-Enhanced ALD *10*

1.1.3.3 Advantages and Challenges of Plasma-Enhanced ALD *10*

1.2 *In Situ* Characterization for Studying ALD Processes *11*

1.2.1 Quartz Crystal Microbalance *12*

1.2.2 Quadrupole Mass Spectrometry (QMS) *13*

1.2.3 Spectroscopic Ellipsometry *14*

1.2.4 Fourier Transform Infrared Spectroscopy *15*

1.2.5 Optical Emission Spectroscopy *15*

1.2.6	Other <i>In Situ</i> Techniques	16
1.3	Conformality of ALD Processes	16
1.3.1	Quantifying the Conformality of ALD Processes	17
1.3.2	Modeling the Conformality of ALD	21
1.3.3	The Conformality of Plasma-Enhanced ALD	24
1.3.4	Conformal Coating of Nanoporous Materials	29
	References	34

Part II Atomic Layer Deposition in Photovoltaic Devices 41

2	Atomic Layer Deposition for High-Efficiency Crystalline Silicon Solar Cells	43
	<i>Bart Macco, Bas W. H. van de Loo, and Wilhelmus M. M. Kessels</i>	
2.1	Introduction to High-Efficiency Crystalline Silicon Solar Cells	43
2.1.1	ALD for Si Homojunction Solar Cells	44
2.1.2	ALD for Si Heterojunction Solar Cells	46
2.1.3	Novel Passivating Contacts and ALD	47
2.1.4	Outline of this Chapter	47
2.2	Nanolayers for Surface Passivation of Si Homojunction Solar Cells	48
2.2.1	Basics of Surface Passivation	48
2.2.1.1	The Physics of Surface Recombination	48
2.2.1.2	Surface Passivation	50
2.2.1.3	Compatibility with Si Homojunction Solar Cells	53
2.2.2	Surface Passivation by ALD Al ₂ O ₃	54
2.2.2.1	ALD of Al ₂ O ₃ for Passivation	55
2.2.2.2	Hydrogenation of Interface Defects	56
2.2.2.3	Interface Engineering by Al ₂ O ₃	57
2.2.2.4	Influence of the Surface Conditions on the Passivation Properties	58
2.2.3	ALD in Solar Cell Manufacturing	59
2.2.3.1	Requirements for Manufacturing in the PV Industry	59
2.2.3.2	High-Throughput ALD Reactors	60
2.2.3.3	ALD Al ₂ O ₃ in the PV Industry	60
2.2.4	New Developments for ALD Passivation Schemes	63
2.2.4.1	ALD Stacks for the Passivation of n^+ Si or n^+ and p^+ Si surfaces	63
2.2.4.2	ALD for the Passivation of Surfaces with Demanding Topologies	64
2.2.4.3	Novel ALD-Based Passivation Schemes	66
2.3	Transparent Conductive Oxides for Si Heterojunction Solar Cells	68
2.3.1	Basics of TCOs in SHJ Solar Cells	69
2.3.1.1	Lateral Conductivity	69
2.3.1.2	Transparency	71
2.3.1.3	Compatibility with SHJ Solar Cells	74
2.3.2	ALD of Transparent Conductive Oxides	74
2.3.2.1	ALD of Doped ZnO	74
2.3.2.2	Beyond Al Doping: Doping by B, Ti, Ga, Hf, and H	77
2.3.2.3	ALD of In ₂ O ₃	78
2.3.3	High-Volume Manufacturing of ALD TCOs	79

2.4	Prospects for ALD in Passivating Contacts	80
2.4.1	Basics of Passivating Contacts	80
2.4.1.1	How to Make a Passivating Contact?	81
2.4.1.2	Requirements of a Passivating Contact	84
2.4.2	ALD for Passivating Contacts	86
2.4.2.1	ALD for Tunneling Oxides	86
2.4.2.2	ALD for Electron-Selective Contacts	87
2.4.2.3	ALD for Hole-Selective Contacts	89
2.5	Conclusions and Outlook	89
	References	90
3	ALD for Light Absorption	101
	<i>Alex Martinson</i>	
3.1	Introduction to Solar Light Absorption	101
3.2	Why ALD for Solar Light Absorbers?	104
3.2.1	Uniformity and Precision of Large-Area Coatings	104
3.2.2	Orthogonalizing Light Harvesting and Charge Extraction	105
3.2.3	Pinhole-Free Ultrathin Films, ETA Cells	107
3.2.4	Chemical Control of Stoichiometry and Doping	107
3.2.5	Low-Temperature Epitaxy	109
3.3	ALD Processes for Visible and NIR Light Absorbers	109
3.3.1	ALD Metal Oxides for Light Absorption	111
3.3.2	ALD Metal Chalcogenides for Light Absorption	111
3.3.2.1	CIS	112
3.3.2.2	CZTS	112
3.3.2.3	Cu ₂ S	112
3.3.2.4	SnS	113
3.3.2.5	PbS	113
3.3.2.6	Sb ₂ S ₃	113
3.3.2.7	CdS	113
3.3.2.8	In ₂ S ₃	114
3.3.2.9	Bi ₂ S ₃	114
3.3.3	Other ALD Materials for Light Absorption	115
3.4	Prospects and Future Challenges	115
	References	115
4	Atomic Layer Deposition for Surface and Interface Engineering in Nanostructured Photovoltaic Devices	119
	<i>Carlos Guerra-Nuñez, Hyung Gyu Park, and Ivo Utke</i>	
4.1	Introduction	119
4.2	ALD for Improved Nanostructured Solar Cells	120
4.2.1	Compact Layer: The TCO/Metal Oxide Interface	121
4.2.2	Blocking Layer: The Metal Oxide/Absorber Interface	126
4.2.3	Surface Passivation and Absorber Stabilization: The Absorber/HTM Interface	130
4.2.4	Atomic Layer Deposition on Quantum Dots	132

- 4.2.5 ALD on Large-Surface-Area Current Collectors: Compact Blocking Layers 134
- 4.3 ALD for Photoelectrochemical Devices for Water Splitting 138
- 4.4 Prospects and Conclusions 142
- References 143

Part III ALD toward Electrochemical Energy Storage 149

5 Atomic Layer Deposition of Electrocatalysts for Use in Fuel Cells and Electrolyzers 151

Lifeng Liu

- 5.1 Introduction 151
- 5.2 ALD of Pt-Group Metal and Alloy Electrocatalysts 153
 - 5.2.1 ALD of Pt Electrocatalysts 154
 - 5.2.1.1 Fabrication and Microstructure 154
 - 5.2.1.2 Electrochemical Performance 157
 - 5.2.2 ALD of Pd Electrocatalysts 168
 - 5.2.3 ALD of Pt-Based Alloy and Core/Shell Nanoparticle Electrocatalysts 169
 - 5.2.3.1 ALD of Pt Alloy Nanoparticle Electrocatalysts 170
 - 5.2.3.2 ALD of Core/Shell Nanoparticle Electrocatalysts 172
- 5.3 ALD of Transition Metal Oxide Electrocatalysts 174
- 5.4 Summary and Outlook 175
- Acknowledgment 178
- References 178

6 Atomic Layer Deposition for Thin-Film Lithium-Ion Batteries 183

Ola Nilson, Knut B. Gandrud, Amund Ruud, and Helmer Fjellvåg

- 6.1 Introduction 183
- 6.2 Coated Powder Battery Materials by ALD 184
- 6.3 Li Chemistry for ALD 186
- 6.4 Thin-Film Batteries 187
- 6.5 ALD for Solid-State Electrolytes 189
 - 6.5.1 Li_2CO_3 189
 - 6.5.2 Li-La-O 189
 - 6.5.3 LLT 189
 - 6.5.4 Li-Al-O (LiAlO_2) 190
 - 6.5.5 $\text{Li}_x\text{Si}_y\text{O}_z$ 191
 - 6.5.6 Li-Al-Si-O 191
 - 6.5.7 LiNbO_3 192
 - 6.5.8 LiTaO_3 192
 - 6.5.9 Li_3PO_4 192
 - 6.5.10 Li_3N 192
 - 6.5.11 LiPON 193

6.5.12	LiF	194
6.6	ALD for Cathode Materials	194
6.6.1	V ₂ O ₅	194
6.6.2	LiCoO ₂	195
6.6.3	MnO _x /Li ₂ Mn ₂ O ₄ /LiMn ₂ O ₄	196
6.6.4	Subsequent Lithiation	196
6.6.5	LiFePO ₄	197
6.6.6	Sulfides	198
6.7	ALD for Anode Materials	198
6.8	Outlook	199
	Acknowledgments	204
	References	204
7	ALD-Processed Oxides for High-Temperature Fuel Cells	209
	<i>Michel Cassir, Arturo Meléndez-Ceballos, Marie-Hélène Chavanne, Dorra Dallel, and Armelle Ringuedé</i>	
7.1	Brief Description of High-Temperature Fuel Cells	209
7.1.1	Solid Oxide Fuel Cells	209
7.1.2	Molten Carbonate Fuel Cells	210
7.2	Thin Layers in SOFC and MCFC Devices	210
7.2.1	General Features	210
7.2.2	Interest of ALD	212
7.3	ALD for SOFC Materials	213
7.3.1	Electrolytes and Interfaces	213
7.3.1.1	Zirconia-Based Materials	213
7.3.1.2	Ceria-Based Materials	214
7.3.1.3	Gallate Materials	215
7.3.2	Electrodes and Current Collectors	215
7.3.2.1	Pt Deposits	215
7.3.2.2	Anode	216
7.3.2.3	Cathode	216
7.4	Coatings for MCFC Cathodes and Bipolar Plates	216
7.5	Conclusion and Emerging Topics	218
	References	218
	Part IV ALD in Photoelectrochemical and Thermoelectric Energy Conversion	223
8	ALD for Photoelectrochemical Water Splitting	225
	<i>Lionel Santinacci</i>	
8.1	Introduction	225
8.2	Photoelectrochemical Cell: Principle, Materials, and Improvements	227
8.2.1	Principle of the PEC	227
8.2.2	Photoelectrode Materials	228
8.2.2.1	Metal Oxides	229

8.2.2.2	Elemental and Compound Semiconductors	229
8.2.2.3	Nitrides	230
8.2.3	Geometry of the Photoelectrodes: Micro- and Nanostructuring	230
8.2.4	Coating and Functionalization of the Photoelectrodes	233
8.3	Interest of ALD for PEC	233
8.3.1	Synthesis of Electrode Materials	234
8.3.2	Nanostructured Photoelectrodes	235
8.3.3	Catalyst Deposition	239
8.3.4	Passivation and Modification of the Junction	240
8.3.5	Photocorrosion Protection	244
8.3.5.1	Protection of Planar Photoanodes	244
8.3.5.2	Protection of Planar Photocathodes	246
8.3.5.3	Protection of Nanostructured Photoelectrodes	246
8.4	Conclusion and Outlook	247
	References	247
9	Atomic Layer Deposition of Thermoelectric Materials	259
	<i>Maarit Karppinen and Antti J. Karttunen</i>	
9.1	Introduction	259
9.1.1	Thermoelectric Energy Conversion and Cooling	259
9.1.2	Designing and Optimizing Thermoelectric Materials	260
9.1.3	Thin-Film Thermoelectric Devices	262
9.2	ALD Processes for Thermoelectrics	263
9.2.1	Thermoelectric Oxide Thin Films	263
9.2.2	Thermoelectric Selenide and Telluride Thin Films	266
9.3	Superlattices for Enhanced Thermoelectric Performance	266
9.4	Prospects and Future Challenges	271
	References	272
	Index	275